

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.10/813,543
Filing Date March 30, 2004
Confirmation No. 8087
Inventor F. Dan Gealy
Assignee Micron Technology, Inc.
Group Art Unit 1792
Examiner Keath T. Chen
Attorney's Docket No. MI22-3685
Title:..... Method for Reducing Physisorption During Atomic Layer Deposition

**RESPONSE TO OCTOBER 8, 2008 ADVISORY ACTION TO ACCOMPANY
A REQUEST FOR CONTINUED EXAMINATION (RCE)**

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

From: Robert C. Hyta (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828